

PATENT ASSIGNMENT

Electronic Version v1.1
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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
Celerity, Inc.	06/15/2009
RECEIVING PARTY DATA	
Name:	Brooks Instrument, LLC
Street Address:	407 West Vine Street
City:	Hatfield
State/Country:	PENNSYLVANIA
Postal Code:	19440
PROPERTY NUMBERS Total: 1	
Property Type	Number
Application Number:	11321238
CORRESPONDENCE DATA	
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<i>Correspondence will be sent via US Mail when the fax attempt is unsuccessful.</i>	
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ATTORNEY DOCKET NUMBER:	11000054-0573
NAME OF SUBMITTER:	Darren W. Collins
Total Attachments: 38 source=Celerity Patent Assignment#page1.tif source=Celerity Patent Assignment#page2.tif source=Celerity Patent Assignment#page3.tif	

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PATENT ASSIGNMENT

For and in consideration of the sum of Ten Thousand Dollars (\$10,000.00) and other good and valuable consideration, the receipt of which is hereby acknowledged, Celerity, Inc., with offices at 2645 Zanker Road, Suite 101, San Jose, CA 95134 (hereinafter "Assignor"), hereby assigns, sells, transfers and sets over effective as of June __, 2009 to Brooks Instrument, LLC, with offices at 407 West Vine Street, Hatfield, PA 19440-0903 (hereinafter "Assignee"), its successors and assigns the entire rights, title and interests in and to the patents and patent applications set forth in Exhibit A, attached hereto and made a part hereof; in and to the inventions covered by such patents and applications; in and to any divisional, continuation, continuation-in-part, or reissue applications corresponding to such patents and applications and any reexamination of such patents and applications; and the right to claim priority based on the filing dates of such applications under the International Convention for the Protection of Industrial Property, the Patent Cooperation Treaty, the European Patent Convention, and all other treaties of like purpose; together with all claims for profits or damages due or accrued by reason of past, present, or future infringements of such patents and applications, with the right to sue for, and collect the same for, Assignee's own use and benefit, and for the benefit of Assignee's successors, assigns, and legal representatives. Assignor will perform such lawful acts and execute all further documents as Assignee may reasonably request, at Assignee's expense, to effectuate fully the assignment of such patents and applications.

IN WITNESS WHEREOF, Assignor has caused this Assignment to be signed by a duly authorized officer.

Celerity, Inc (Assignor)

By: Tim Harris

Printed name: Tim Harris

Title: Chief Executive Officer

Date: 6-15-09

EXHIBIT A

SCHEDULE OF PATENTS AND TRADEMARKS**Patents**

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Pending	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	KR	PCT	KR	2007-7003058	07-Jul-05		
Granted	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	19	PRI	US	10/887,591	09-Jul-04	7412986	19-Aug-08
Abandoned	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	TW	ORD	TW	94123260	08-Jul-05	1278606	11-Apr-07
Pending	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	JP	PCT	JP	520494/2007	07-Jul-05		
Abandoned	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	EP	PCT	EP	5772286	07-Jul-05		
Abandoned	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	CN	PCT	CN	580029957.8	07-Jul-05		

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Inactive	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	WO	ORD	PCT	US2005/024084	07-Jul-05		
Abandoned	Flow Verifier	METHOD AND SYSTEM FOR FLOW MEASUREMENT AND VALIDATION OF A MASS FLOW CONTROLLER	C2044-7024	SG	PCT	SG	200700059-9	07-Jul-05		
Granted	Flow Verifier	Method and System for Flow Measurement and Validation of Mass Flow Controller	C2044-7024	30	CIP	US	10/946,031	21-Sep-04	7424895	16-Sep-08
Abandoned	Flow Verifier	RATE OF RISE SENSOR	C1138-7007		PRI	US				
Granted	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	19	PRI	US	11/012750	15-Dec-04	7150201	19-Dec-06
Granted	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	20	CON	US	11/341826	27-Jan-06	7287434	30-Oct-07
Abandoned	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	TW	ORD	TW	94144182	14-Dec-05		
Abandoned	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	SG	PCT	SG	200702892-1	29-Nov-05		
Pending	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	KR	PCT	KR	2007-7016097	29-Nov-05		
Abandoned	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	JP	PCT	JP	546711/2007	29-Nov-05		
Abandoned	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	EP	PCT	EP	5826076.1	29-Nov-05		
Abandoned	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	CN	PCT	CN	580043027.8	29-Nov-05		
Inactive	Flow Verifier	SYSTEM AND METHOD FOR MEASURING FLOW	C2044-7017	WO	ORD	PCT	US2005/043148	29-Nov-05		
Abandoned	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	EP	PCT	EP	5811910.8	13-Oct-05		

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Published	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	US	PCT	US	11/664,550	03-Apr-07		
Abandoned	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	TW	ORD	TW	94135754	13-Oct-05		
Abandoned	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	SG	PCT	SG	200701620-7	13-Oct-05		
Inactive	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	WO	ORD	PCT	US2005/037130	13-Oct-05		
Abandoned	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	MY	ORD	MY	P120070586	16-Apr-07		
Abandoned	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	JP	PCT	JP	536969/07	13-Oct-05		
Abandoned	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	CN	PCT	CN	580034213.5	13-Oct-05		
Abandoned	HBSC	METHOD AND SYSTEM FOR WAFER TEMPERATURE CONTROL	C2044-7026	KR	PCT	KR	2007-7008380	13-Oct-05		
Inactive	Heater	COMPONENT HEATER FOR USE IN SEMICONDUCTOR MANUFACTURING EQUIPMENT	C2044-7001	EP	PCT	EP	99945336.8	03-Sep-99	1118051	17-Mar-04

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No.	Filing Date	Patent No.	Issue Date
Pending	Heater	COMPONENT HEATER FOR USE IN SEMICONDUCTOR MANUFACTURING EQUIPMENT	C2044-7001	JP	PCT	JP	2000-569296	03-Sep-03		
Abandoned	Heater	COMPONENT HEATER FOR USE IN SEMICONDUCTOR MANUFACTURING EQUIPMENT	C2044-7001	NL	EPP	NL	99945336.8	03-Sep-99	1118051	17-Mar-04
Abandoned	Heater	COMPONENT HEATER FOR USE IN SEMICONDUCTOR MANUFACTURING EQUIPMENT	C2044-7001	TW	ORD	TW	88115459	08-Sep-99	131484	01-May-01
Abandoned	Heater	COMPONENT HEATER FOR USE IN SEMICONDUCTOR MANUFACTURING EQUIPMENT	C2044-7001	GB	EPP	GB	99945336.8	03-Sep-99	1118051	17-Mar-04
Granted	Heater	COMPONENT HEATER FOR USE IN SEMICONDUCTOR MANUFACTURING EQUIPMENT	C2044-7001	19	PRI	US	09/150458	09-Sep-98	6078030	20-Jun-00
Expired	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	0	PRO	US	60/707628	12-Aug-05		
Abandoned	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	TW	ORD	TW	95129519	11-Aug-06		
Abandoned	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	SG	PCT	SG	200703341-8	11-Aug-06		
Inactive	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	WO	ORD	PCT	US2006/031579	11-Aug-06		

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Abandoned	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	MY	ORD	MY	P120063906	11-Aug-06		
Pending	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	KR	PCT	KR	2007-7011301	11-Aug-06		
Pending	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	JP	PCT	JP	526275/2008	31-May-07		
Abandoned	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	CN	PCT	CN	680001605.6	11-Aug-06		
Abandoned	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	10	ORD	US	11/503873	11-Aug-06		
Abandoned	LFC	FLOW MEASUREMENT AND CONTROL WITH BUBBLE DETECTION	C1138-7012	EP	PCT	EP	6801387.9	11-Aug-06		
Abandoned	LFC	LIQUID FLOW CONTROLLER	C1138-7002	US	PRI	US	07/906922	30-Jun-92	5303731	19-Apr-94
Unfiled	LFC	PRESSURE MIX RATIO CONTROLLER	C1138-7010	19	PRI	US				
Inactive	LFC	ULTRASONIC FLOW SENSOR	C1138-7009	WO	ORD	PCT	US2006/031291	10-Aug-06		
Abandoned	LFC	ULTRASONIC FLOW SENSOR	C1138-7009	TW	ORD	TW	95129338	10-Aug-06		
Expired	LFC	ULTRASONIC FLOW SENSOR	C1138-7009	0	PRO	US	60/707574	12-Aug-05		
Granted	LFC	ULTRASONIC FLOW SENSOR	C1138-7009	10	ORD	US	11/502308	10-Aug-06	7360448	22-Apr-08
Abandoned	LFC	ULTRASONIC FLOW SENSOR	C1138-7009	20	CON	US	12/148537	18-Apr-08		
Abandoned	LFC	ULTRASONIC FLOW SENSOR	C1138-7009	MY	ORD	MY	P120063862	10-Aug-06		
Abandoned	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	EP	PCT	EP	5762540.2	28-Jun-05		

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Inactive	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	20	CON	US				
Granted	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	19	PRI	US	10/878974	28-Jun-04	7117104	03-Oct-06
Abandoned	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	TW	ORD	TW	94121591	28-Jun-05		
Granted	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	SG	PCT	SG	541292	28-Jun-05	128389	29-Feb-08
Inactive	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	WO	ORD	PCT	US2005/022944	28-Jun-05		
Abandoned	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	MY	ORD	MY	PI20052927	28-Jun-05		
Pending	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	JP	PCT	JP	519361/2007	28-Jun-05		
Abandoned	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	CN	PCT	CN	0580027755.X	28-Jun-05		
Pending	LFC	ULTRASONIC LIQUID FLOW CONTROLLER	C1138-7006	KR	PCT	KR	2007-7001933	28-Jun-05		
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	NL	EPP	NL	951066	20-Jun-00	1214635	02-Apr-03
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	FR	EPP	FR	951066	20-Jun-00	1214635	02-Apr-03
Granted	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	20	CON	US	10/062080	31-Jan-02	6714878	30-Mar-04
Granted	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	19	PRI	US	09/351120	10-Jul-99	6389364	14-May-02
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW	C2044-7007	GB	EPP	GB	951066	20-Jun-00	1214635	02-Apr-03

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
		CONTROLLER								
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	TW	ORD	TW	89113530	10-Jul-00	NI-131920	03-Sep-01
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	SG	PCT	SG	200108041-5	20-Jun-00	85973	27-Feb-04
Pending	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	JP	PCT	JP	2001-510060	20-Jun-00		
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	CN	PCT	CN	810184.1	20-Jun-00	810184.1	19-Oct-05
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	DE	EPP	DE	951066	20-Jun-00	60001977.2	02-Apr-03
Granted	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	KR	PCT	KR	2002-7000234	20-Jun-00	10-0684539	13-Feb-07
Inactive	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	EP	PCT	EP	951066	20-Jun-00	1214635	02-Apr-03
Abandoned	MFC	A SYSTEM AND METHOD FOR A DIGITAL MASS FLOW CONTROLLER	C2044-7007	IT	EPP	IT	951066	20-Jun-00	1214635	02-Apr-03
Expired	MFC	ADJUSTABLE LAMINAR FLOW BYPASS	C2044-7046	NL	ORD	NL	8400089	11-Jan-84	193641	04-May-00
Abandoned	MFC	APPARATUS FOR HANDLING PROCESS	U0128-7008	GB	EPC	GB	94930532	30-Sep-94	722552	04-Jul-01

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
		FLUID								
Granted	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008		CON	US	08/557378	13-Nov-95	5803507	08-Sep-98
Abandoned	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	NL	EPC	NL	94930532	30-Sep-94	722552	04-Jul-01
Abandoned	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	KR	PCT	KR	701790/1996	30-Sep-94		
Abandoned	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	JP	PCT	JP	07-510916	30-Sep-94	3431631	23-May-03
Abandoned	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	IT	EPC	IT	94930532	30-Sep-94	722552	04-Jul-01
Abandoned	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	DE	EPC	DE	94930532	30-Sep-94	69427645.6	04-Jul-01
Abandoned	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	FR	EPC	FR	94930532	30-Sep-94	722552	04-Jul-01
Inactive	MFC	APPARATUS FOR HANDLING PROCESS FLUID	U0128-7008	EP	PCT	EP	94930532	30-Sep-94	722552	04-Jul-01
Pending	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	KR	PCT	KR	2007-7002945	07-Jul-05		
Granted	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	20	CON	US	11/788,201	19-Apr-07	7412336	12-Aug-08
Granted	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	19	PRI	US	10/887048	08-Jul-04	7222029	22-May-07
Abandoned	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	TW	ORD	TW	94123274	08-Jul-05		

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Inactive	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	WO	ORD	PCT	US2005/024085	07-Jul-05		
Abandoned	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	JP	PCT	JP	520495/2007	07-Jul-05		
Abandoned	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	EP	PCT	EP	5772203.5	07-Jul-05		
Abandoned	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	CN	PCT	CN	2.0058002293e+011	07-Jul-05		
Pending	MFC	ATTITUDE INSENSITIVE FLOW DEVICE SYSTEM AND METHOD	C2044-7023	SG	PCT	SG	564483	07-Jul-05		
Expired	MFC	ELECTROMAGNETIC VALVE WITH PERMANENT MAGNET ARMATURE	C1138-7013	19	PRI	US	711280	22-Oct-85	4690371	01-Sep-87
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	SG	PCT	SG	584541	20-Nov-95	42612	27-Apr-99
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	42	DIV	US	08/686231	23-Jul-96		
Granted	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	41	DIV	US	08/685260	23-Jul-96	5850850	22-Dec-98
Inactive	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	EP	PCT	EP	95940785.9	20-Nov-95	800672	07-Jun-00
Granted	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	40	DIV	US	08/685322	23-Jul-96	5765283	16-Jun-98

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Granted	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	US	PCT (CIP)	US	2365159	20-Nov-95	5901741	11-May-99
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	19	PRI	US	08/365861	29-Dec-94	5660207	26-Aug-97
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	GB	EPP	GB	95940785.9	20-Nov-95	800672	07-Jun-00
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	TW	ORD	TW	84112299	20-Nov-95	NL-081535	05-Nov-03
Inactive	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	WO	ORD	PCT	US1995/015157	20-Nov-95		
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	KR	PCT	KR	1997-7004536	20-Nov-95	323958	28-Jan-02
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	JP	PCT	JP	1995-520980	20-Nov-95	3717520	09-Sep-05
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	IT	EPP	IT	95940785.9	20-Nov-95	800672	07-Jun-00
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	FR	EPP	FR	95940785.9	20-Nov-95	800672	07-Jun-00
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	CN	PCT	CN	95197568.4	20-Nov-95	ZL95197568	30-Jun-04

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	1C	DIV	CN	410038447.4	20-Nov-95	410038447.4	29-Aug-07
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7032	DE	EPP	DE	95940785.9	20-Nov-95	69517447	07-Jun-00
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7045	2G	EDV	GB	99108928.5	20-Nov-95		
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7045	2D	EDV	DE	99108928.5	20-Nov-95		
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7045	F2	EDV	FR	99108928.5	20-Nov-95		
Abandoned	MFC	FLOW CONTROLLER, PARTS OF FLOW CONTROLLER, AND RELATED METHOD	C2044-7045	E2	DIV	EP	99108928.5	20-Nov-95	940741	09-Jan-08
Inactive	MFC	FLOW SENSOR	U0128-7035	WO	ORD	PCT	US2003/022643	18-Jul-03		
Abandoned	MFC	FLOW SENSOR	U0128-7035	20	CON	US	10/988,173	12-Nov-04		
Expired	MFC	FLOW SENSOR	U0128-7035		PRO	US	60/397461	19-Jul-02		
Abandoned	MFC	FLOW SENSOR	U0128-7035	KR	PCT	KR	2005-7000895	18-Jul-03		
Pending	MFC	FLOW SENSOR	U0128-7035	JP	PCT	JP	523170/2004	18-Jul-03		
Published	MFC	FLOW SENSOR	U0128-7035	EP	PCT	EP	3765796.2	18-Jul-03		
Abandoned	MFC	FLOW SENSOR	U0128-7035	CN	PCT	CN	3817189.9	18-Jul-03	3817189.9	12-Dec-07
Granted	MFC	FLOW SENSOR	U0128-7035	10	ORD	US	10/623147	18-Jul-03	6826953	07-Dec-04

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			7035							
Pending	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	KR	PCT	KR	2005-7018084	25-Mar-04		
Published	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	20	CON	US	11/856,585	17-Sep-07		
Granted	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040		PRI	US	1838541	26-Mar-03	7043374	09-May-06
Granted	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	TW	ORD	TW	93108097	25-Mar-04	1241469	11-Oct-05
Inactive	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	WO	ORD	PCT	US2004/009144	25-Mar-04		
Granted	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	40	DIV	US	11/051209	04-Feb-05	7272512	18-Sep-07
Published	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	JP	PCT	JP	509282/2006	25-Mar-04		
Abandoned	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	EP	PCT	EP	4758325.7	25-Mar-04		
Abandoned	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	CN	PCT	CN	480014377.7	25-Mar-04		
Abandoned	MFC	FLOW SENSOR SIGNAL CONVERSION	U0128-7040	SG	PCT	SG	200506245-0	25-Mar-04		
Inactive	MFC	FLUID FLOW METER	C2044-7044	E1	DIV	EP	99108929.3	20-Nov-95	940742	10-Apr-02
Abandoned	MFC	FLUID FLOW METER	C2044-7044	FR	EDV	FR	99108929.3	20-Nov-95	940742	10-Apr-02
Abandoned	MFC	FLUID FLOW METER	C2044-7044	DE	EDV	DE	99108929.3	20-Nov-95	69526378	10-Apr-02
Abandoned	MFC	FLUID FLOW METER	C2044-7044	GB	EDV	GB	99108929.3	20-Nov-95	940742	10-Apr-02
Granted	MFC	FLUID FLOW METER WITH REDUCED ORIENTATION SENSITIVITY	C2044-7038	JP	ORD	JP	1997-149659	06-Jun-97	4034379	02-Nov-07
Granted	MFC	FLUID FLOW METER WITH REDUCED ORIENTATION SENSITIVITY	C2044-7038	19	PRI	US	08/691061	01-Aug-96	5763774	09-Jun-98

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Expired	MFC	FLUID FLOW STABILIZING APPARATUS	C1138-7004	US	PRI	US	07/167572	04-Mar-88	4858643	22-Aug-89
Granted	MFC	FLUID MASS FLOW METER DEVICE WITH REDUCED ATTITUDE SENSITIVITY	C2044-7029	24	CON	US	07/912007	10-Jul-92	5191793	09-Mar-93
Pending	MFC	Mass Flow Controller with Improved Dynamic MASS FLOW	CINST-7005	19	PRI	United States of America	12/197,888	25-Aug-08		
Expired	MFC	CONTROLLER WITH VERTICAL PURIFIER	U0128-7029		CON	US	08/758971	02-Dec-96	5730181	24-Mar-98
Abandoned	MFC	MASS FLOW METER OR CONTROLLER WITH INCLINATION SENSOR	C1138-7008	20	CON	US	12/120,975	15-May-08		
Granted	MFC	MASS FLOW METER OR CONTROLLER WITH INCLINATION SENSOR	C1138-7008	19	PRI	US	11/377,911	16-Mar-06	7409871	12-Aug-08
Published	MFC	MASS FLOW METER OR CONTROLLER WITH INCLINATION SENSOR	C1138-7008	TW	ORD	TW	96108901	15-Mar-07		
Abandoned	MFC	MASS FLOW METER OR CONTROLLER WITH INCLINATION SENSOR	C1138-7008	WO	ORD	PCT	US2007/006712	16-Mar-07		
Pending	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	JP	PCT	JP	2001-509947	20-Jun-00		
Granted	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	19	PRI	US	09/350746	09-Jul-99	6575027	10-Jun-03
Abandoned	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	TW	ORD	TW	89113547	07-Jul-00	NI-131525	28-Aug-01
Granted	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	KR	PCT	KR	2002-7000239	20-Jun-00	10-0684515	13-Feb-07

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Abandoned	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	EP	PCT	EP	951067.8	20-Jun-00		
Abandoned	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	CN	PCT	CN	8011267.3	20-Jun-00		
Abandoned	MFC	MASS FLOW SENSOR INTERFACE CIRCUIT	C2044-7006	SG	PCT	SG	200108047-2	20-Jun-00	85978	30-Jan-04
Expired	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7007		PRO	US	60/182306	14-Feb-00		
Granted	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	TW	ORD	TW	90103216	14-Feb-01	170268	20-May-03
Granted	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020		ORD	US	09/783439	14-Feb-01	6539792	01-Apr-03
Inactive	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	WO	ORD	PCT	US01/04609	14-Feb-01		
Granted	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	KR	PCT	KR	2002-7010507	14-Feb-01	10-0808727	22-Feb-08
Pending	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	JP	PCT	JP	560630/01	14-Feb-01		
Abandoned	MFC	METHOD AND APPARATUS FOR BALANCING RESISTANCE	U0128-7020	EP	PCT	EP	1910613.7	14-Feb-01		
Inactive	MFC	METHOD AND APPARATUS FOR REDUCING HYSTERESIS IN A SOLENOID ACTUATED DEVICE	U0128-7022		PRI	US				

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Granted	MFC	METHOD AND SYSTEM FOR A MASS FLOW CONTROLLER WITH REDUCED PRESSURE SENSITIVITY	C2044-7020	19	PRI	US	10/886836	08-Jul-04	7216019	08-May-07
Abandoned	MFC	METHOD AND SYSTEM FOR A MASS FLOW CONTROLLER WITH REDUCED PRESSURE SENSITIVITY	C2044-7020	TW	ORD	TW	94123276	08-Jul-05		
Inactive	MFC	METHOD AND SYSTEM FOR A MASS FLOW CONTROLLER WITH REDUCED PRESSURE SENSITIVITY	C2044-7020	WO	ORD	PCT	US2005/024134	07-Jul-05		
Granted	MFC	METHOD AND SYSTEM FOR DRIVING A SOLENOID	C2044-7005	19	PRI	US	09/351111	10-Jul-99	6404612	11-Jun-02
Inactive	MFC	METHOD FOR COMPLENSATING THE TEMPERATURE COEFFICI	C2044-7022	0	PRO	US				
Expired	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034		PRO	US	60/397285	19-Jul-02		
Granted	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	10	ORD	US	10/622080	17-Jul-03	7073392	11-Jul-06
Pending	MFC	Methods and Apparatus for Pressure Compensation in a Mass Flow Controller	U0128-7034	42	CON	US	12/233,405	18-Sep-08		

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Granted	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	40	DIV	US	11/148053	08-Jun-05	7273063	25-Sep-07
Abandoned	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	SG	PCT	SG		17-Jul-03	109196	31-Jan-07
Abandoned	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	CN	PCT	CN	03822352.X	17-Jul-03		
Abandoned	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	G1	DIV	SG	200601750-3	17-Jul-03		
Abandoned	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	EP	PCT	EP	3765703.8	17-Jul-03		
Inactive	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	WO	ORD	PCT	US2003/022435	17-Jul-03		
Pending	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A	U0128-7034	JP	PCT	JP	523546/2004	17-Jul-03		

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
		MASS FLOW CONTROLLER								
Abandoned	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	KR	PCT	KR	2005-7000906	17-Jul-03		
Granted	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	41	DIV	US	11/843418	22-Aug-07	7434477	14-Oct-08
Granted	MFC	METHODS AND APPARATUS FOR PRESSURE COMPENSATION IN A MASS FLOW CONTROLLER	U0128-7034	TW	ORD	TW	92119634	18-Jul-03	I223056	01-Nov-04
Inactive	MFC	MICRO-ORFICE BY PASS FOR MASS MODULAR SUBSTRATE GAS PANEL HAVING MANIFOLD CONNECTIONS IN A COMMON PLANE	U0128-7036		PRO	US	60/406132	27-Aug-02		
Expired	MFC	MULTI-GAS FLOW DEVICE	C1138-7019	0	PRO	US	60/842283	05-Sep-06		
Published	MFC	MULTI-GAS FLOW DEVICE	C1138-7019	10	ORD	US	11/850505	05-Sep-07		
Published	MFC	MULTI-GAS FLOW DEVICE	C1138-7019	TW	ORD	TW	96133001	05-Sep-07		
Published	MFC	MULTI-GAS FLOW DEVICE	C1138-7019	WO	ORD	PCT	US2007/019333	05-Sep-07		
Expired	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7002		PRO	US	60/143478	12-Jul-99		

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Inactive	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7016	50	REX	US				
Granted	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7016	TW	ORD	TW	89113822	12-Jul-00	130212	08-Aug-01
Granted	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7016	JP	PCT	JP	509951/01	12-Jul-00	3615517	12-Nov-04
Abandoned	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7016	EP	PCT	EP	945351.5	12-Jul-00		
Granted	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7016		ORD	US	09/616819	12-Jul-00	6425281	30-Jul-02
Inactive	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7016	WO	ORD	PCT	US00/19028	12-Jul-00		
Abandoned	MFC	PRESSURE INSENSITIVE GAS CONTROL SYSTEM	U0128-7033		CON	US	10/187411	01-Jul-02		
Published	MFC	SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)	C2044-7016	IC	DIV	CN	2.0081000135e+011	23-May-03		
Abandoned	MFC	SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)	C2044-7016	CN	PCT	CN	ZL03814867.6	23-May-03		
Pending	MFC	SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)	C2044-7016	JP	PCT	JP	2004-507769	23-May-03		
Abandoned	MFC	SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)	C2044-7016	TW	ORD	TW	92114020	23-May-03	1280354	01-May-07

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Granted	MFC	SLOTTED FLOW RESTRICTOR FOR A MASS FLOW METER (as amended by the ISA in the ISR dated 9-16-03)	C2044-7016	US	PCT	US	10/515328	23-May-03	7124647	24-Oct-06
Expired	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7017		PRO	US	60/285801	24-Apr-01		
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	40	DIV	US	11/092144	29-Mar-05	7114511	03-Oct-06
Abandoned	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	CN	PCT	CN	2810540	24-Apr-02		
Abandoned	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	EP	PCT	EP	2764338.6	24-Apr-02		
Pending	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	JP	PCT	JP	2002-584094	24-Apr-02		
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	21	CON	US	11/749386	16-May-07	7380564	03-Jun-08
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	20	CON	US	11/091824	28-Mar-05	7231931	19-Jun-07
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030		ORD	US		24-Apr-02	6962164	08-Nov-05
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	TW	ORD	TW	91108305	23-Apr-02	181838	12-Nov-03
Inactive	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	WO	ORD	PCT	US02/13010	24-Apr-02		
Abandoned	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7030	KR	PCT	KR	2003-7014001	24-Apr-02		

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Inactive	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7060	E1	DIV	EP	4002135.4	24-Apr-02	1457856	23-Nov-05
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7060	DE	EDV	DE	4002135.4	24-Apr-02	60207609.9	23-Nov-05
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7060	IE	EDV	IE	4002135.4	24-Apr-02	1457856	23-Nov-05
Granted	MFC	SYSTEM AND METHOD FOR A MASS FLOW CONTROLLER	U0128-7060	NL	EDV	NL	4002135.4	24-Apr-02	1457856	23-Nov-05
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	SG	PCT	SG	200108045-6	21-Jun-00	85977	27-Feb-04
Granted	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	19	PRI	US	09/351098	10-Jul-99	6445980	03-Sep-02
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	TW	ORD	TW	89113538	10-Jul-00	NI-156972	27-Sep-02
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	NL	EPP	NL	955906.3	21-Jun-00	1196833	27-Aug-03
Granted	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	KR	PCT	KR	2002-7000370	21-Jun-00	10-0621830	13-Sep-06

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Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	IT	EPP	IT	955906.3	21-Jun-00	1196833	27-Aug-03
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	DE	EPP	DE	955906.3	21-Jun-00	60004855.1	27-Aug-03
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	FR	EPP	FR	955906.3	21-Jun-00	1196833	27-Aug-03
Inactive	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	EP	PCT	EP	955906.3	21-Jun-00	1196833	27-Aug-03
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	CN	PCT	CN	810175.2	21-Jun-00	810175.2	04-Jan-06
Abandoned	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	GB	EPP	GB	955906.3	21-Jun-00	1196833	27-Aug-03
Pending	MFC	SYSTEM AND METHOD FOR A VARIABLE GAIN PROPORTIONAL-INTEGRAL (PI) CONTROLLER	C2044-7004	JP	PCT	JP	2001-510061	21-Jun-00		
Abandoned	MFC	SYSTEM AND METHOD FOR FILTERING OUTPUT IN MASS FLOW CONTROLLERS AND MASS FLOW METERS	C2044-7010	10	ORD	US	50679	26-Apr-02	6865520	08-Mar-05

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Granted	MFC	SYSTEM AND METHOD FOR FILTERING OUTPUT IN MASS FLOW CONTROLLERS AND MASS FLOW METERS	C2044-7010	20	CON	US	2723524	26-Aug-04	7113895	26-Sep-06
Granted	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	CN	PCT	CN	3814900.1	23-May-03	ZL03814900.1	15-Oct-08
Granted	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	20	CON	US	11/129166	13-May-05	7363182	22-Apr-08
Granted	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	10	ORD	US	10/444249	23-May-03	7243035	10-Jul-07
Abandoned	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	TW	ORD	TW	92113996	23-May-03	1274143	21-Feb-07
Pending	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	KR	PCT	KR	2004-7019027	23-May-03		
Abandoned	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	EP	PCT	EP	3734166.6	23-May-03		
Pending	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	JP	PCT	JP	2004-507802	23-May-03		
Abandoned	MFC	SYSTEM AND METHOD FOR MASS FLOW DETECTION DEVICE CALIBRATION	C2044-7015	SG	PCT	SG	200406847-4	23-May-03	108077	

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Granted	MFC	SYSTEM AND METHOD FOR SENSOR RESPONSE LINEARIZATION	C2044-7008	KR	PCT	KR	2002-7000306	20-Jun-00	10-0620282	29-Aug-06
Granted	MFC	SYSTEM AND METHOD FOR SENSOR RESPONSE LINEARIZATION	C2044-7008	19	PRI	US	09/350747	09-Jul-99	6449571	10-Sep-02
Abandoned	MFC	SYSTEM AND METHOD FOR SENSOR RESPONSE LINEARIZATION	C2044-7008	SG	PCT	SG	200108042-3	20-Jun-00	85974	30-Jan-04
Pending	MFC	SYSTEM AND METHOD FOR SENSOR RESPONSE LINEARIZATION	C2044-7008	JP	PCT	JP	2001-509948	20-Jun-00		
Abandoned	MFC	SYSTEM AND METHOD FOR SENSOR RESPONSE LINEARIZATION	C2044-7008	EP	PCT	EP	951068.6	20-Jun-00		
Abandoned	MFC	SYSTEM AND METHOD FOR SENSOR RESPONSE LINEARIZATION	C2044-7008	CN	PCT	CN	810113.2	20-Jun-00	810113.2	15-Jun-05
Abandoned	MFC	SYSTEM AND METHOD FOR SENSOR RESPONSE LINEARIZATION	C2044-7008	TW	ORD	TW	89113537	07-Jul-00	NI-133298	26-Sep-01
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	1D	EDV	DE	3016602.9	21-Jun-00	60036649.9	03-Oct-07
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	40	DIV	US	09/755994	05-Jan-01		
Granted	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	20	CON	US	1780467	06-Dec-01	6681787	27-Jan-04
Granted	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	19	PRI	US	09/350744	09-Jul-99	6343617	05-Feb-02

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	SG	PCT	SG	200108048-0	21-Jun-00	85979	31-Mar-04
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	IG	EDV	GB	3016602.9	21-Jun-00	1359487	03-Oct-07
Granted	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	41	DIV	US	225265	05-Feb-02	6640822	04-Nov-03
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	TW	ORD	TW	89113546	07-Jul-00	NI-154643	01-May-02
Granted	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	KR	PCT	KR	2002-7000296	21-Jun-00	10-0718209	15-May-07
Pending	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	JP	PCT	JP	2001-510059	21-Jun-00		
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	II	EDV	IE	3016602.9	21-Jun-00	1359487	03-Oct-07
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	F1	EDV	FR	3016602.9	21-Jun-00	1359487	03-Oct-07
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	E1	DIV	EP	3016602.9	21-Jun-00	1359487	03-Oct-07
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	CN	PCT	CN	811323.8	21-Jun-00	811323.8	05-Apr-06

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Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	I1	EDV	IT	3016602.9	21-Jun-00	1359487	03-Oct-07
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7003	N1	EDV	NL	3016602.9	21-Jun-00	1359487	03-Oct-07
Inactive	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7028	EP	PCT	EP	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7028	FR	EPP	FR	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7028	DE	EPP	DE	939986.6	21-Jun-00	60005849.2	08-Oct-03
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7028	IE	EPP	IE	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7028	IT	EPP	IT	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7028	NL	EPP	NL	939986.6	21-Jun-00	1212665	08-Oct-03
Abandoned	MFC	SYSTEM AND METHOD OF OPERATION OF A DIGITAL MASS FLOW CONTROLLER	C2044-7028	GB	EPP	GB	939986.6	21-Jun-00	1212665	08-Oct-03
Pending	MFC	System for and Method of Providing a Wide-Range Flow Controller	C1138-7020	10	ORD	US	12/249,821	10-Oct-08		

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Expired	MFC	SYSTEM FOR AND METHODS OF PROVIDING A WIDE-RANGE FLOW CONTROLLER	C1138-7020	0	PRO	US	60/978956	10-Oct-07		
Pending	MFC	Thermal Flow Meter	CINST-7001	10	ORD	United States of America	12/193,584	18-Aug-08		
Pending	MFC	Thermal Mass Flow Controller	CINST-7001	0	PRO	United States of America	61/080,270	13-Jul-08		
Abandoned	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7013	DE	EPC	DE	93924335.8	15-Oct-93	69327538.3	05-Jan-00
Abandoned	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7013	GB	EPC	GB	93924335.8	15-Oct-93	664879	05-Jan-00
Granted	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7013	KR	PCT	KR	701451/1995	15-Oct-93	323962	28-Jan-02
Abandoned	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7013	IT	EPC	IT	93924335.8	15-Oct-93	664879	05-Jan-00

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Abandoned	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7013	FR	EPC	FR	93924335.8	15-Oct-93	664879	05-Jan-00
Inactive	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7013	EP	PCT	EP	93924335.8	15-Oct-93	664879	05-Jan-00
Granted	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7013	JP	PCT	JP	510311/94	15-Oct-93	3279567	22-Feb-02
Granted	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7014		CON	US	08/815323	10-Mar-97	6044701	04-Apr-00
Abandoned	MFC	THERMAL MASS FLOW CONTROLLER HAVING ORTHOGONAL THERMAL MASS FLOW SENSOR	U0128-7015		CON	US	09/499762	08-Feb-00		
Granted	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	19	PRI	US	10/887040	08-Jul-04	7133785	07-Nov-06
Abandoned	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	CN	PCT	CN	2.0058002996e+011	07-Jul-05		
Abandoned	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	EP	PCT	EP	5769581.9	07-Jul-05		
Abandoned	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	JP	PCT	JP	520482/2007	07-Jul-05		
Pending	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	KR	PCT	KR	2007-7002967	07-Jul-05		
Inactive	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	WO	ORD	PCT	US2005/024033	07-Jul-05		

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Abandoned	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	SG	PCT	SG	200700115-9	07-Jul-05		
Abandoned	MFC	VALVE CONTROL SYSTEM AND METHOD	C2044-7019	TW	ORD	TW	94123259	08-Jul-05		
Expired	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7025		PRO	US	60/397139	19-Jul-02		
Expired	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039		PRO	US	60/436207	23-Dec-02		
Granted	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	20	CON	US	10/978156	29-Oct-04	7082824	01-Aug-06
Granted	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	10	ORD	US	10/622004	16-Jul-03	6845659	25-Jan-05
Abandoned	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	SG	PCT	SG		16-Jul-03	109197	31-Aug-07
Inactive	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	WO	ORD	PCT	US2003/022337	16-Jul-03		
Abandoned	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	KR	PCT	KR	2005-7001009	16-Jul-03		
Abandoned	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	EP	PCT	EP	3765648.5	16-Jul-03		
Abandoned	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	CN	PCT	CN	03819614.X	16-Jul-03	03819614.X	24-Oct-07
Granted	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	TW	ORD	TW	92119635	18-Jul-03	1222514	21-Oct-04
Pending	MFC	VARIABLE RESISTANCE SENSOR WITH COMMON REFERENCE LEG	U0128-7039	JP	PCT	JP	523492/2004	16-Jul-03		
Abandoned	Other	GAS FLOW CONTROL APPARATUS	C1138-7003	US	PRI	US	1092990	03-Apr-89	4913192	03-Apr-90

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Granted	Other	INVENTORY CONTROL PROBE	C2044-7043	70	DES	US	29/057079	16-Jul-96	D390138	03-Feb-98
Expired	Pressure	FLOW RESPONSIVE TRANSMITTER AND INDICATOR	C2044-7041	19	PRI	US	1435586	21-Jan-87	4898036	06-Feb-90
Granted	Pressure	METHOD OF MAKING THIN FILM PIEZORESISTIVE SENSOR	C2044-7033	19	PRI	US	09/291468	14-Apr-99	6319743	20-Nov-01
Abandoned	Pressure	METHOD OF MAKING THIN FILM PIEZORESISTIVE SENSOR	C2044-7033	EP	PCT	EP	925951.6	13-Apr-00		
Abandoned	Pressure	METHOD OF MAKING THIN FILM PIEZORESISTIVE SENSOR	C2044-7033	JP	PCT	JP	2000-611045	13-Apr-00	3730868	14-Oct-05
Abandoned	Pressure	METHOD OF MAKING THIN FILM PIEZORESISTIVE SENSOR	C2044-7033	KR	PCT	KR	2001-7013160	13-Apr-00	432465	11-May-04
Abandoned	Pressure	METHOD OF MAKING THIN FILM PIEZORESISTIVE SENSOR	C2044-7033	TW	ORD	TW	89106988	28-Apr-00	NI-145002	01-Aug-01
Abandoned	Pressure	METHOD OF MAKING THIN FILM PIEZORESISTIVE SENSOR	C2044-7033	SG	PCT	SG	200106292-6	13-Apr-00	84198	31-May-04
Expired	Pressure	PRESSURE MONITORING APPARATUS HAVING A HALL-EFFECT DETECTOR	C2044-7040	19	PRI	US	1394649	28-Oct-85	4745811	24-May-88
Pending	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	SG	PCT	SG		11-Apr-05		
Abandoned	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	CN	PCT	CN	580011775.8	11-Apr-05		
Pending	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	TW	ORD	TW	94112264	18-Apr-05		

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Inactive	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	WO	ORD	PCT	US2005/012282	11-Apr-05		
Pending	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	KR	PCT	KR	2006-7024081	11-Apr-05		
Pending	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	JP	PCT	JP	508449/2007	11-Apr-05		
Published	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	EP	PCT	EP	5735372.4	11-Apr-05		
Granted	Pressure	PRESSURE SENSOR DEVICE AND METHOD	C2044-7018	19	PRI	US	10/827026	19-Apr-04	7131334	07-Nov-06
Granted	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	20	CON	US	10/952508	28-Sep-04	7043994	16-May-06
Granted	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	19	PRI	US	10/178170	24-Jun-02	7000482	21-Feb-06
Abandoned	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	41	DIV	US	11/392,253	29-Mar-06	7395716	08-Jul-08
Granted	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	40	DIV	US	10/996023	23-Nov-04	7073388	11-Jul-06
Abandoned	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	CN	PCT	CN	3817613	23-Jun-03		
Abandoned	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	TW	ORD	TW	92116992	23-Jun-03		
Pending	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	JP	PCT	JP	2004-516145	23-Jun-03		
Abandoned	Pressure	VARIABLE CAPACITANCE MEASURING DEVICE	C2044-7000	30	CIP	US	10/228612	27-Aug-02	6837111	04-Jan-05
Abandoned	Process sensing	VACUUM SENSOR	C2044-7031	TW	ORD	TW	91102111	06-Feb-02	NI-172695	01-Mar-03
Granted	Process sensing	VACUUM SENSOR	C2044-7031	US	PCT	US	2834923	31-Jan-02	6964187	15-Nov-05

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Expired	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7027		PRO	US	60/293356	24-May-01		
Abandoned	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	CN	PCT	CN	2810484.6	23-May-02	ZL02810484.6	16-Jul-08
Granted	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	41	DIV	US	11/504,175	15-Aug-06	7424894	16-Sep-08
Granted	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	40	DIV	US	11/174753	05-Jul-05	7143774	05-Dec-06
Granted	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	21	CON	US	11/651231	09-Jan-07	7360551	22-Apr-08
Granted	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	20	CON	US	10/832949	27-Apr-04	6941965	13-Sep-05
Published	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	J2	DIV	JP	2008-027627	23-May-02		
Granted	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	TW	ORD	TW	91111088	24-May-02	196734	04-Jun-04

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Inactive	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	WO	ORD	PCT	US02/16289	23-May-02		
Abandoned	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	KR	PCT	KR	2003-7014994	23-May-02		
Granted	RFS	Method and Apparatus for Providing a Determined Ratio of Process Fluids	U0128-7031	JP	PCT	JP	2002-591927	23-May-02	4209688	31-Oct-08
Granted	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031		ORD	US	10/154433	23-May-02	6752166	22-Jun-04
Abandoned	RFS	METHOD AND APPARATUS FOR PROVIDING A DETERMINED RATIO OF PROCESS FLUIDS	U0128-7031	EP	PCT	EP	2739349.5	23-May-02		
Published	RFS	Method and Apparatus for Providing a Determined Ratio of Process Fluids	U0128-7031	J1	DIV	JP	2008-027621	23-May-02		
Abandoned	ROR	METHOD AND APPARATUS FOR DETERMINING A RATE OF FLOW OF GAS BY A RATE OF CHANGE OF PRESSURE	U0128-7041		CON	US	689062	03-Feb-97	5925829	20-Jul-99
Expired	Vacuum	ADAPTIVE PRESSURE CONTROL SYSTEM	C2044-7037	19	PRI	US	06/736224	20-May-85	4720807	19-Jan-88
Published	Vacuum	An Improved Electronic Interface For Use With Dual Electrode Capacitance Diaphragm Gauges	C2044-7013	CN	PCT	CN	ZL03817033.7	11-Jun-03		

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Pending	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	JP	PCT	JP	2004-513064	12-Jun-03		
Abandoned	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	TW	ORD	TW	92115978	12-Jun-03		
Abandoned	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	CN	PCT	CN	3816966.5	12-Jun-03	3816966.5	25-Apr-08
Granted	Vacuum	AN IMPROVED TEMPERATURE REGULATOR FOR USE WITH A PRESSURE SENSING DEVICE	C2044-7012	19	PRI	US		13-Jun-02	6701790	09-Mar-04
Granted	Vacuum	CAPACITANCE MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE	C2044-7047	FR	ORD	FR	8809402	11-Jul-88	8809402	03-Sep-93
Granted	Vacuum	CAPACITANCE MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE	C2044-7047	DE	ORD	DE	P3838333.0	11-Nov-88	3838333	10-Dec-90
Granted	Vacuum	CAPACITANCE MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE	C2044-7047	JP	ORD	JP	63-280250	04-Nov-88	1701368	14-Oct-92
Abandoned	Vacuum	CAPACITANCE MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE	C2044-7047	KR	ORD	KR	16383/88	09-Dec-88	66935	26-Oct-93
Expired	Vacuum	CAPACITANCE MANOMETER HAVING STRESS RELIEVE FOR FIXED ELECTRODE	C2044-7047	19	PRI	US	07/189780	03-May-88	4823603	25-Apr-89

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Abandoned	Vacuum	DEVICE AND SYSTEM FOR PRESSURE SENSING AND CONTROL	C2044-7011	19	PRI	US	10/805742	22-Mar-04		
Granted	Vacuum	DUAL BALANCED CAPACITANCE MANOMETERS FOR SUPPRESSING VIBRATION EFFECTS	C2044-7035	19	PRI	US	08/088317	07-Jul-93	5396803	14-Mar-95
Pending	Vacuum	ELECTRONIC INTERFACE FOR USE WITH DUAL ELECTRODE CAPACITANCE DIAPHRAGM GAUGES	C2044-7013	JP	PCT	JP	2004-513790	11-Jun-03		
Abandoned	Vacuum	ELECTRONIC INTERFACE FOR USE WITH DUAL ELECTRODE CAPACITANCE DIAPHRAGM GAUGES	C2044-7013	TW	ORD	TW	92115982	12-Jun-03		
Granted	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7013	19	PRI	US	-474540	13-Jun-02	6734659	11-May-04
Pending	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	KR	PCT	KR	2004-7019462	29-May-03		
Granted	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	40	DIV	US	10/848739	19-May-04	7010983	14-Mar-06

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Granted	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	21	CON	US	11/369,885	07-Mar-06	7490518	17-Feb-09
Published	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	20	CON	US	11/321,238	29-Dec-05		
Granted	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	19	PRI	US	-527500	31-May-02	6910381	28-Jun-05
Abandoned	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	SG	PCT	SG	200406848-2	29-May-03	108078	31-Jan-08
Pending	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	JP	PCT	JP	2004-509366	29-May-03		
Abandoned	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	EP	PCT	EP	3731440.8	29-May-03		

Status	Product Category	Title	Case Number	Sub Case	Case Type	Country	Application No	Filing Date	Patent No	Issue Date
Abandoned	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	CN	PCT	CN	03815563.X	29-May-03		
Abandoned	Vacuum	SYSTEM AND METHOD OF OPERATION OF AN EMBEDDED SYSTEM FOR A DIGITAL CAPACITANCE DIAPHRAGM GAUGE	C2044-7014	TW	ORD	TW	92114786	30-May-03		
Granted	Valve	BUTTERFLY VALVE HAVING IMPROVED SEALING	C2044-7036	19	PRI	US	07/701200	16-May-91	5118078	02-Jun-92
Abandoned	Valve	CHARACTERISTICS INTEGRATED GAS PANEL	10294-7003		PRI	US	08/404485	17-Mar-95	5605179	25-Feb-97
Inactive	Valve	INTEGRATED GAS PANEL	10294-7003	WO	ORD	PCT	US96/01945	13-Feb-96		
Abandoned	Valve	PENDULUM VALVE WITH A FULL RANGE OF NORMAL POSITION CONTROL	C2044-7009	TW	ORD	TW	91108434	24-Apr-02	NI-177978	09-Sep-03
Granted	Valve	PENDULUM VALVE WITH A FULL RANGE OF NORMAL POSITION CONTROL	C2044-7009	10	ORD	US	09/952083	12-Sep-01	7004453	28-Feb-06
Granted	Valve	REGULATOR FLOW CONTROL	C2044-7042	19	PRI	US	07/872350	23-Apr-92	5218991	15-Jun-93
Abandoned	Valve	THROTTLE VALVE	C2044-7034	JP	ORD	JP	1992-350321	01-Dec-92	3274895	01-Feb-02
Granted	Valve	THROTTLE VALVE	C2044-7034	19	PRI	US	08/078365	16-Jun-93	5413139	09-May-95
Granted	Valve	VALVE MECHANISM	C2044-7039	19	PRI	US	08/682170	16-Jul-96	5785297	28-Jul-98
Published	WVDM	System and Method for Producing and Delivering Vapor	C2044-7030	19	PRI	US	11/349,068	07-Feb-06		

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Abandoned	WVDM	VAPOR DELIVERY SYSTEM AND METHOD	C2044-7030	WO	ORD	PCT	US2007/003143	07-Feb-07		
Pending	WVDM	VAPOR DELIVERY SYSTEM AND METHOD	C2044-7030	TW	ORD	TW	96104382	07-Feb-07		